Kyung-Mun Kang

List of Publications by Year
in descending order

20 papers	272 citations	933447 10 h-index	940533 16 g-index
20 all docs	20 docs citations	20 times ranked	423 citing authors

#	Article	IF	Citations
1	The role of oxygen defects engineering via passivation of the Al2O3 interfacial layer for the direct growth of a graphene-silicon Schottky junction solar cell. Applied Materials Today, 2022, 26, 101267.	4.3	11
2	Al/F codoping effect on the structural, electrical, and optical properties of ZnO films grown via atomic layer deposition. Applied Surface Science, 2021, 535, 147734.	6.1	21
3	Structural, electrical, and optical properties of Si-doped ZnO thin films prepared via supercycled atomic layer deposition. Materials Science and Engineering B: Solid-State Materials for Advanced Technology, 2021, 273, 115401.	3.5	9
4	Effect of Hydrogen Doping on the Gateâ€Tunable Memristive Behavior of Zinc Oxide Films with and without F or N Doping. Physica Status Solidi (A) Applications and Materials Science, 2021, 218, 2000702.	1.8	4
5	Film thickness effect in c-axis oxygen vacancy-passivated ZnO prepared via atomic layer deposition by using H2O2. Applied Surface Science, 2020, 529, 147095.	6.1	12
6	Effective Oxygen-Defect Passivation in ZnO Thin Films Prepared by Atomic Layer Deposition Using Hydrogen Peroxide. Journal of the Korean Ceramic Society, 2019, 56, 302-307.	2.3	4
7	Study on properties of Ga/F-co-doped ZnO thin films prepared using atomic layer deposition. Thin Solid Films, 2018, 660, 913-919.	1.8	18
8	Low temperature method to passivate oxygen vacancies in un-doped ZnO films using atomic layer deposition. Thin Solid Films, 2018, 660, 852-858.	1.8	15
9	Oxygen vacancy-passivated ZnO thin film formed by atomic layer deposition using H2O2. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2018, 36, .	2.1	16
10	N-doped Al2O3 thin films deposited by atomic layer deposition. Thin Solid Films, 2018, 660, 657-662.	1.8	17
11	Effect of Atomic Layer Deposition Temperature on the Growth Orientation, Morphology, and Electrical, Optical, and Band-Structural Properties of ZnO and Fluorine-Doped ZnO Thin Films. Journal of Physical Chemistry C, 2018, 122, 377-385.	3.1	22
12	Thickness-dependent growth orientation of F-doped ZnO films formed by atomic layer deposition. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2016, 34, .	2.1	10
13	In Situ Incorporation of Pt Nanoparticles in Fluorine-doped SnO2 Nanocomposite Thin Films by a One-step Synthesis. Chemistry Letters, 2015, 44, 782-784.	1.3	1
14	The CO gas sensing properties of direct-patternable SnO₂ films containing graphene or Ag nanoparticles. New Journal of Chemistry, 2015, 39, 2256-2260.	2.8	20
15	Non-laminated growth of chlorine-doped zinc oxide films by atomic layer deposition at low temperatures. Journal of Materials Chemistry C, 2015, 3, 8336-8343.	5.5	22
16	Structural, Electrical, and Optical Properties of Photochemical Metal-Organic-Deposited ZnO Thin Films Incorporated with Ag Nanoparticles and Graphene. ECS Journal of Solid State Science and Technology, 2015, 4, N55-N59.	1.8	6
17	Anion-controlled passivation effect of the atomic layer deposited ZnO films by F substitution to O-related defects on the electronic band structure for transparent contact layer of solar cell applications. Solar Energy Materials and Solar Cells, 2015, 132, 403-409.	6.2	47
18	Directly patternable SnO2 thin films incorporating Pt nanoparticles. Materials Research Bulletin, 2014, 52, 6-10.	5.2	4

#	Article	IF	Citations
19	Enhanced hole injection into indium-free organic red light-emitting diodes by fluorine-doping-induced texturing of a zinc oxide surface. Journal of Materials Chemistry C, 2014, 2, 8344-8349.	5.5	12
20	Thickness-dependent Electrical, Structural, and Optical Properties of ALD-grown ZnO Films. Journal of the Microelectronics and Packaging Society, 2014, 21, 31-35.	0.1	1